

B. Clean Specification Changes

Please replace paragraph(s) starting at page 7, line 22 and ending at page 8, line 11 with the following paragraph(s):

ab In order to focus the electron beams (see 4 in FIG. 1); or to form an exact electron beam spot on a periphery of the screen, the foregoing electrodes have various voltages applied thereto for forming the pre-focus lens, the main focus lens, and the quadrupole lens by means of their potential differences, wherein the third electrode 113 is connected as follows for having a voltage applied thereto. Since one end of the wire 122 is welded to the stem pin 121 the dynamic voltage applied thereto, and the other end of the wire 122 is welded to the third electrode 113, the third electrode has the dynamic voltage at the stem pin applied thereto (see FIG. 4). In order to prevent the inside wall of the neck part (see FIG. 3) from being scratched by the wire 122 during the electron gun sealing process (see 5 in FIG. 5), the wire has an evasive form so that the wire does not come into contact with the inside wall of the neck part. In order to prevent generating noise during the movement of the electron beams 4, the wire has an evasive form so as not to come into contact with the bead glass for preventing generation of contact noise by vibration between the wire and the bead glass.

Please replace paragraph(s) starting at page 8, line 23 and ending at page 9, line 16 with the following paragraph(s):

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In order to focus the electron beams 4, or to form an exact electron beam spot on a periphery of the screen, the foregoing electrodes have various voltages applied thereto for forming the pre-focus lens, the main focus lens, and the quadrupole lens by means of their potential differences, wherein the dynamic electrode 215 is connected as follows for having a voltage applied thereto. Since one end of the first wire 222a is welded to the stem pin 221a the dynamic voltage applied thereto, and the other end of the first wire 222a is welded to the dynamic electrode 215, the dynamic electrode has the dynamic voltage at the stem pin applied thereto (see FIG. 8), and since one end of the second wire 222b is welded to the stem pin 221b the static voltage applied thereto, and the other end of the second wire 222b is welded to the third electrode 213, the third electrode has the static voltage at the stem pin applied thereto (see FIG. 8). In order to prevent the inside wall of the neck part 3 from being scratched by the first wire 222a and the second wire 222b during the electron gun 5 sealing process, the first wire 222a and the second wire 222b have evasive forms so that the first wire 222a and the second wire 222b do not come into contact with the inside wall of the neck part. In order to prevent generation of noise occurred during the electron beams 4 move, the first wire 222a and the second wire 222b have evasive forms so as not to come into contact with the bead glass 219 for preventing generation of contact noise by vibration between the first wire 222a and the second wire 222b and the bead glass 219.
